



ECE695: Reliability Physics of Nano-Transistors

Lecture 12: Field dependence of NBTI

Muhammad Ashraf Alam
alam@purdue.edu

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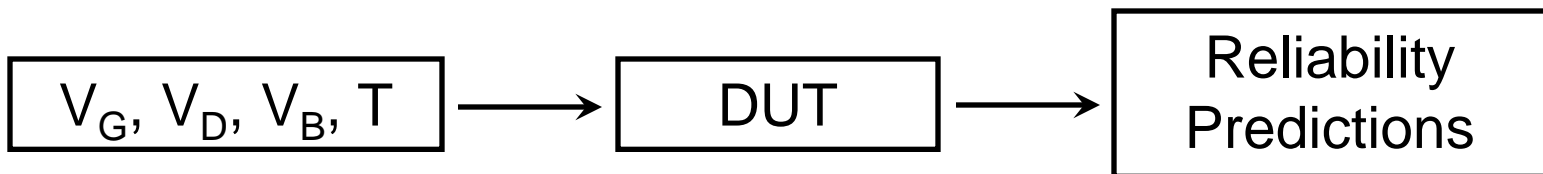
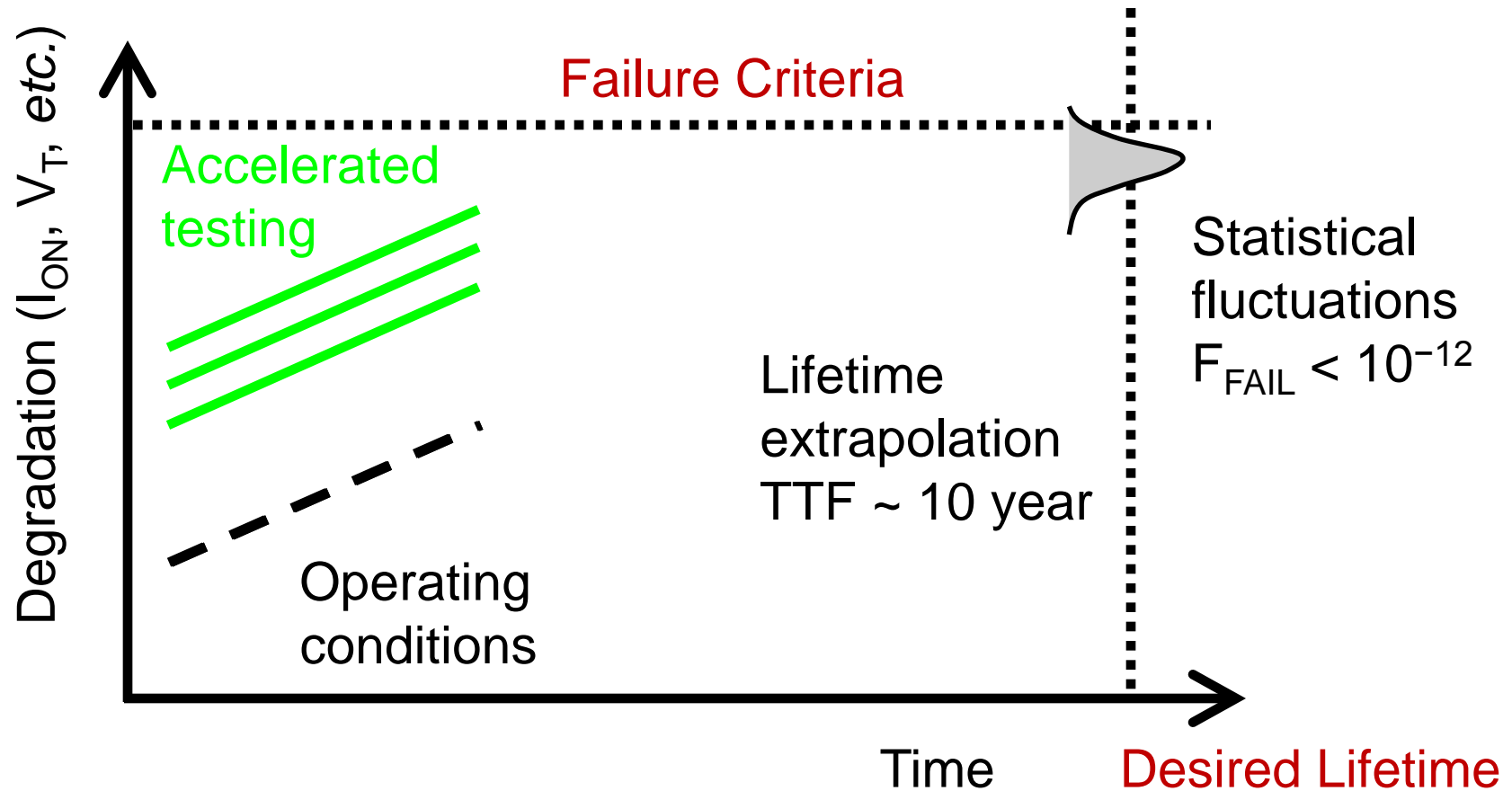
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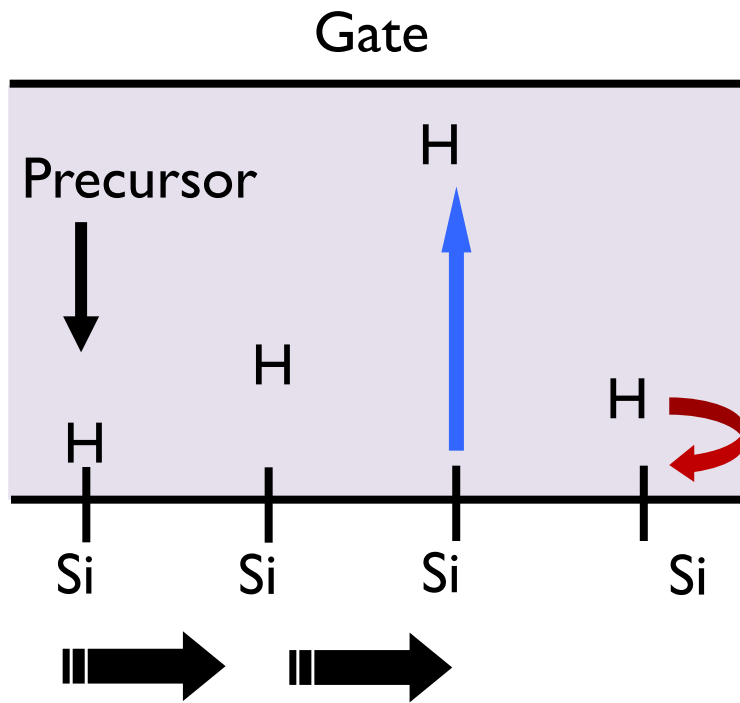
Outline

1. Background: Field dependent degradation
2. Components of field-dependent dissociation:
3. Interpreting experiments
4. Voltage acceleration factors
5. Conclusion

Importance of voltage acceleration



NBTI mechanism : interface-trap generation



Dissociation of Si-H bonds create Si* and H

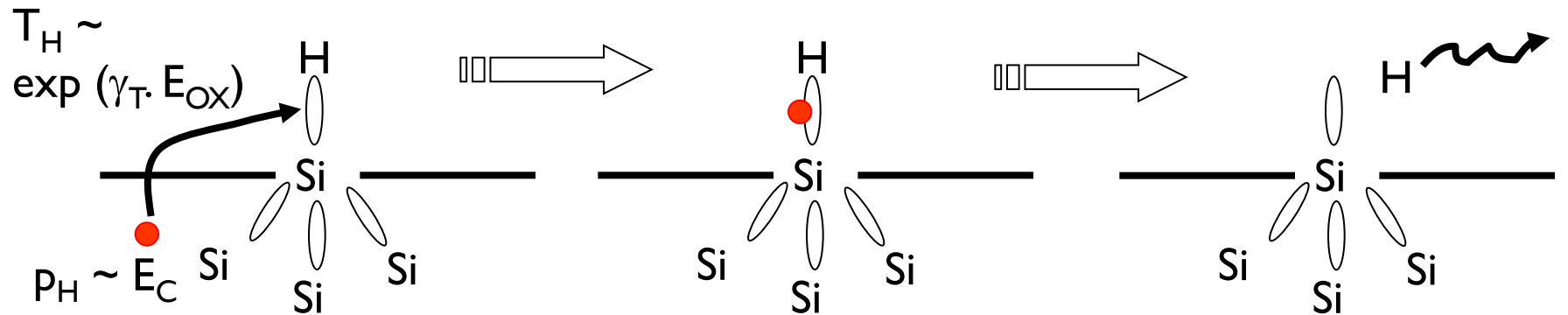
H diffuses away and leave Si* (N_{IT} generation)

H reacts back and form Si-H (N_{IT} anneal)

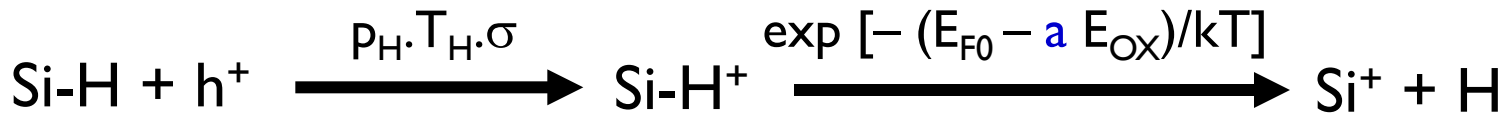
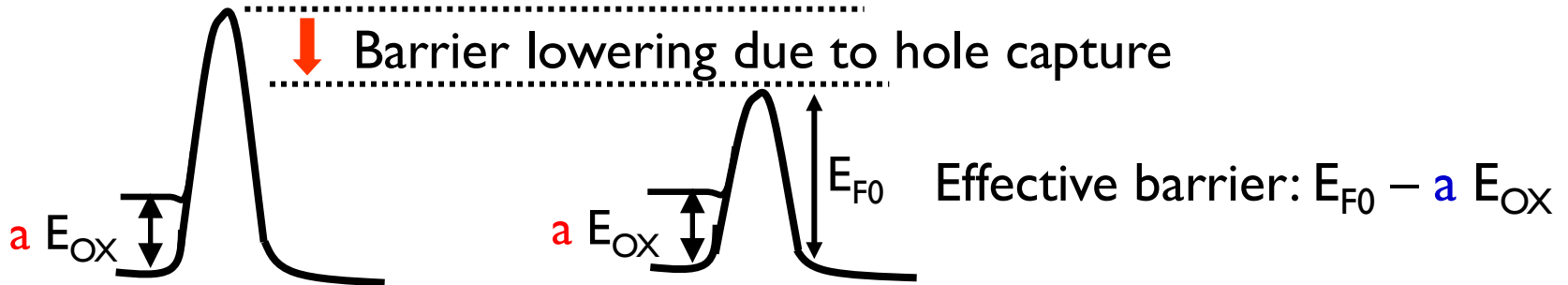
N_{IT} generation depends on H removal from surface

S. Ogawa et. al., PRB, p.4298, 1995

Field-dependent bond dissociation



Barrier lowering due to hole capture



$$k_F \sim E_C \exp(\gamma E_{OX}) \exp(-E_{F0}/kT)$$

$$\gamma = \gamma_T + a/kT$$

$$a = 0.6 - 1.2$$

$$\gamma_T = 0.16 - 0.18,$$

Interface traps with H₂ diffusion

Generation of traps

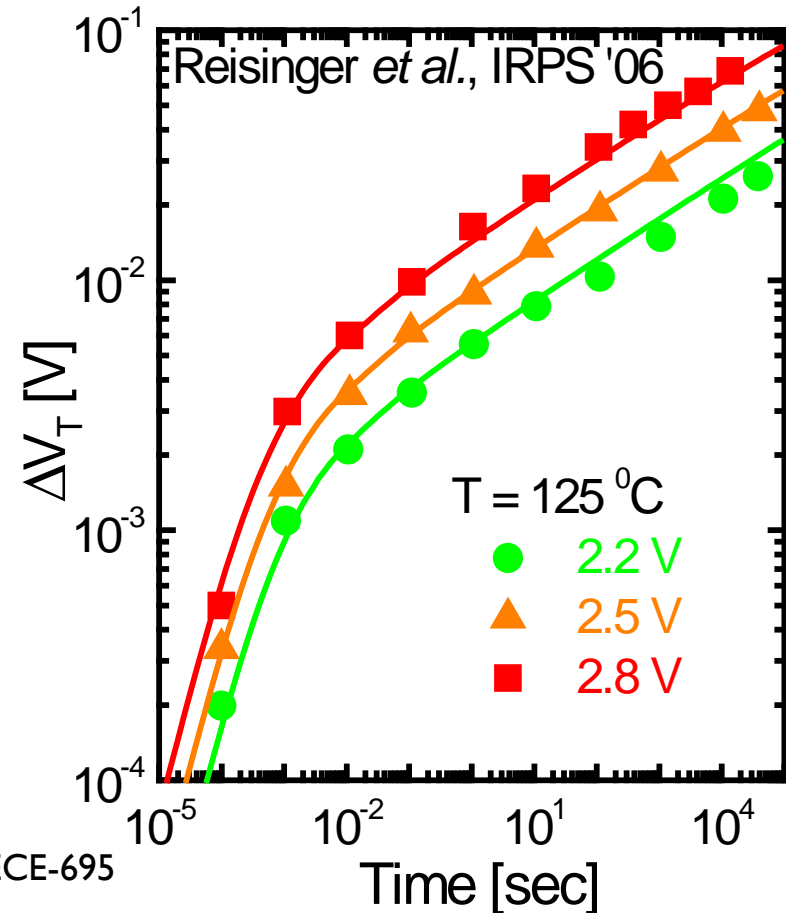
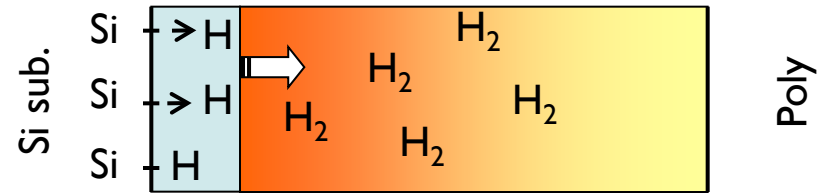
$$N_{IT}(t) \propto \left(\frac{k_F N_0}{2k_R} \right)^{2/3} (D_{H_2} t)^{1/6}$$

$$k_F = k_0 p_h T \sigma e^{-(E_{F0} - a \mathcal{E}_{ox}) / k_B T}$$

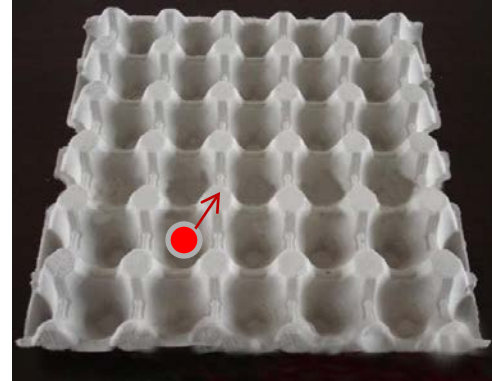
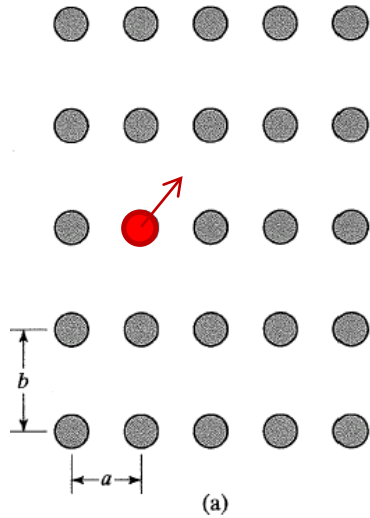
k_Rfield independent

D_{H_2}field independent

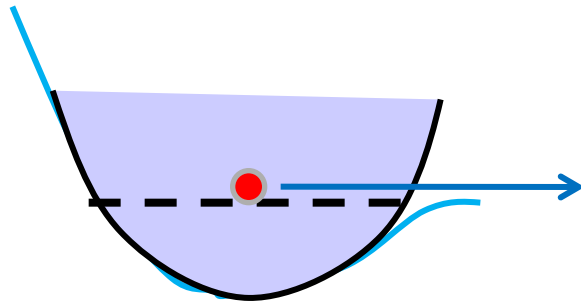
Focus on forward dissociation



Aside: Three types of bond dissociation

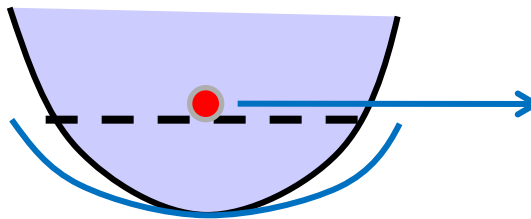


Field induced



NBTI, HCI, TDDB
(partly ... Small)

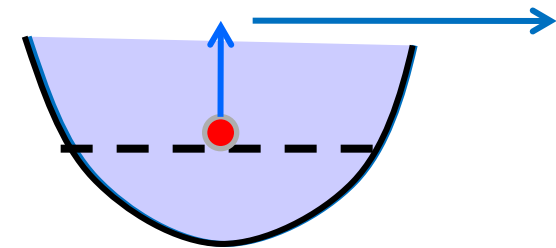
Charge State



NBTI primarily

Alam ECE-695

Radiation or
e-h recombination



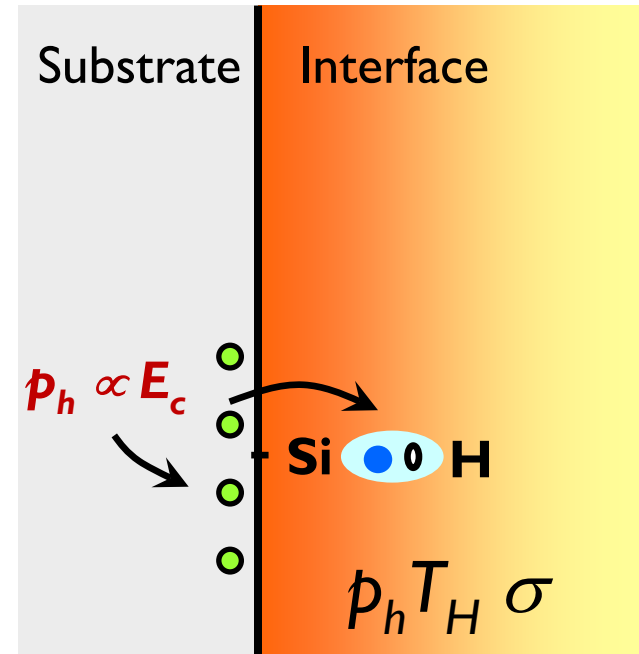
HCI, TDDB, etc.

Outline

1. Background: Field dependent degradation
2. Components of field-dependent dissociation:
 - Tunneling
 - Hole density
 - Bond polarization factor
3. Interpreting experiments & voltage acceleration
4. Conclusion

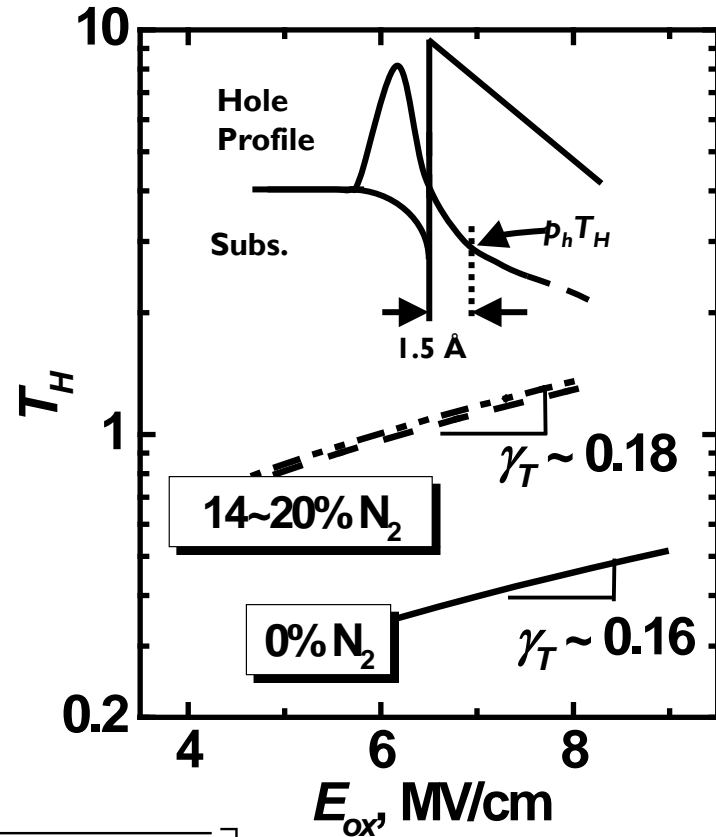
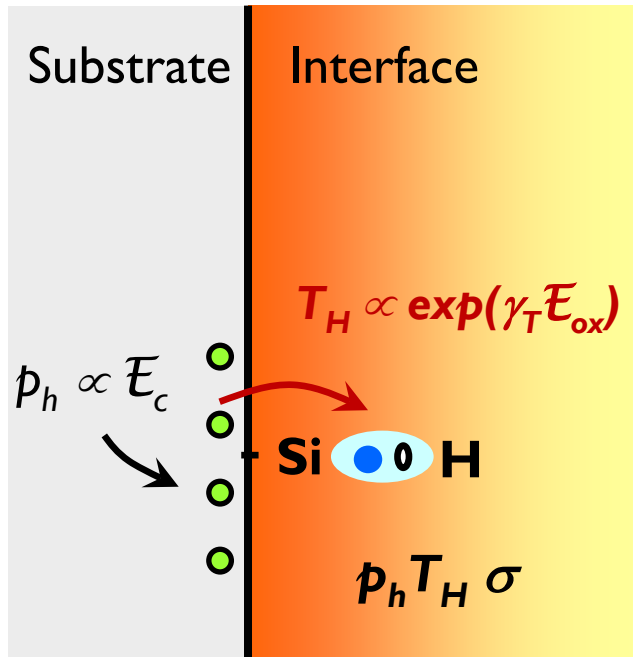
Inversion charges in the channel

$$Q_{inv} = qp_h$$
$$= C_{ox} (V_G - V_T) \propto \mathcal{E}_c$$



A rather simple form inversion charges,
appropriate for the phenomenological description

Inversion and capture into the bonds



$$Q_{inv} = qp_h = C_{ox} (V_G - V_{th}) \propto E_c$$

$$T_H \sim \exp \left[-2 \int_0^{t_{int}} dx \frac{\sqrt{2qm_{ox} (\Phi_B - xE_{ox})}}{\hbar} \right]$$

γ_T reduces with Φ_B

$$\ln T_H \sim -\frac{2\sqrt{2qm_{ox}\Phi_B}}{\hbar} t_{int} + \left[\sqrt{\frac{m_{ox}}{2q\Phi_B}} \frac{qt_{int}^2}{\hbar} E_{ox} - \dots \dots \dots \right]$$

Polarization of free atoms: calculate a

$$k_F = k_0 p_h T \sigma e^{-(E_{F0} - aE_{ox})/k_B T}$$

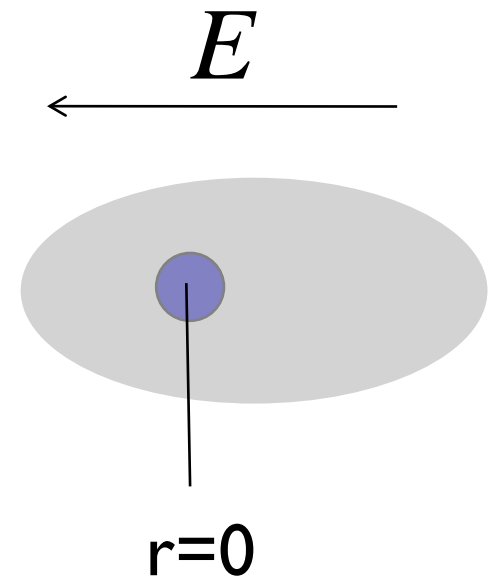
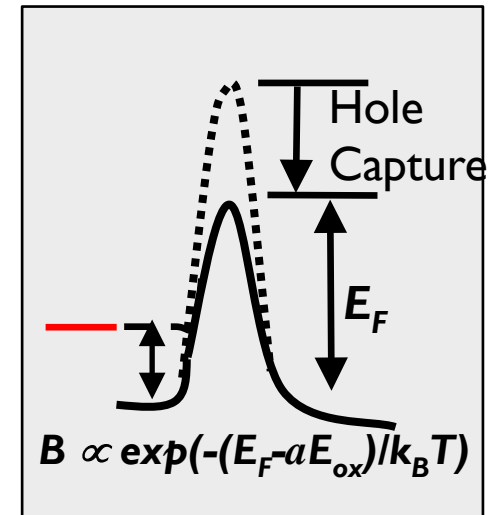
$$p = -q \int r \times n(r) dr$$

Finite contribution because the electron charge is not symmetric

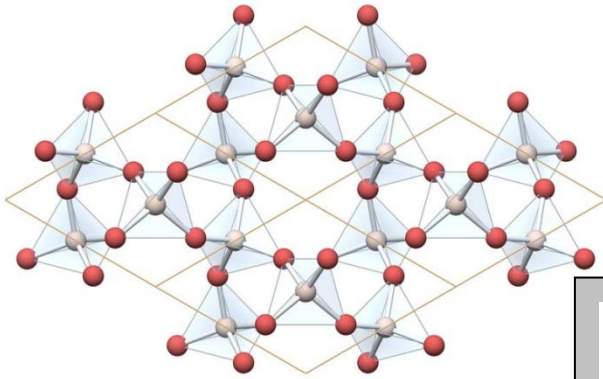
$$p = \alpha \mathcal{E}_{loc} + \beta \mathcal{E}_{loc}^2$$

↑
Polarizability

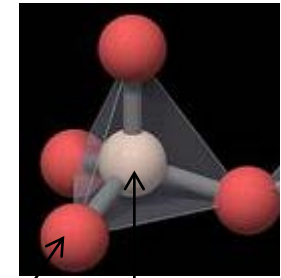
↖
Hyper-Polarizability



Aside: Polarity of SiO₂ and SiH bonds

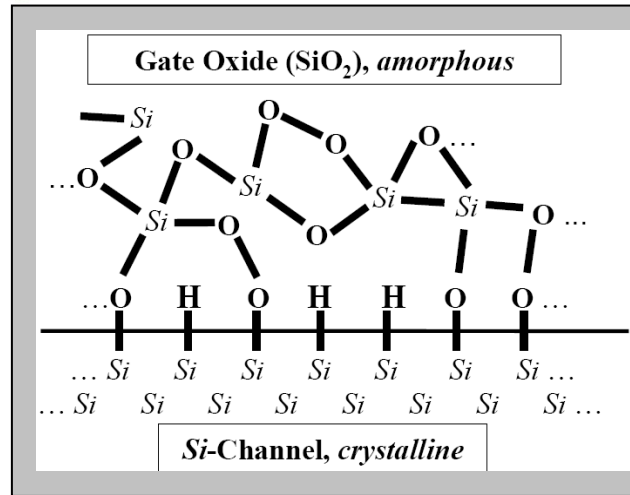


Polar bonds individually **randomized** in bulk



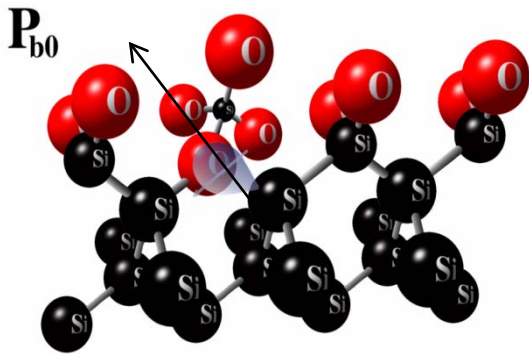
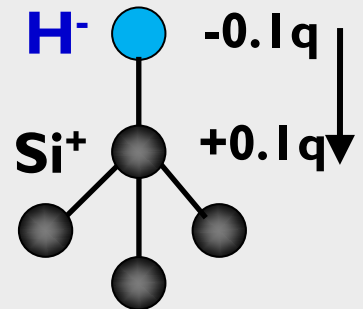
Si
oxygen

E_{ox}



$Q^* = 0.1q$

$p_m = 0.15 \text{ eÅ}$



Polar bonds individually **aligned** at interface

Dipole moments in a polar material

Force balance for charges

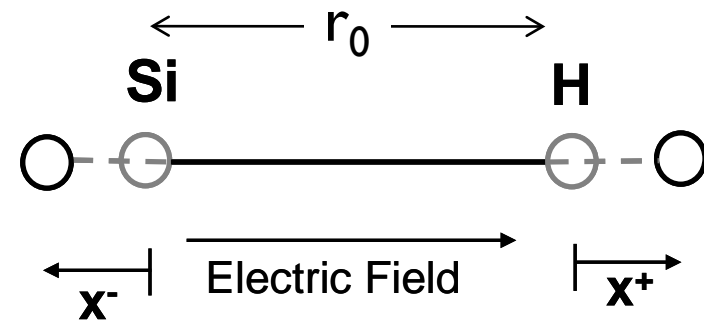
$$F_{Q^*} = -F_{-Q^*} = Q^* \times \mathbf{E}_{loc} - \gamma \times (x^+ - x^-) = 0$$

electrostatic
Spring term

equilibrium

Additional displacement ...

$$(x^+ - x^-) = Q^* \times \mathbf{E}_{loc} / \gamma$$



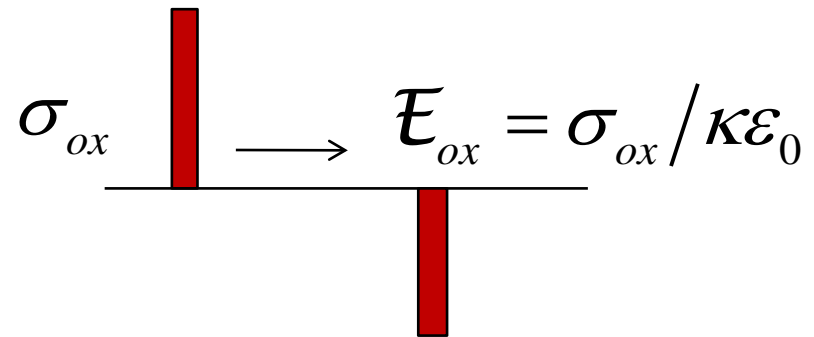
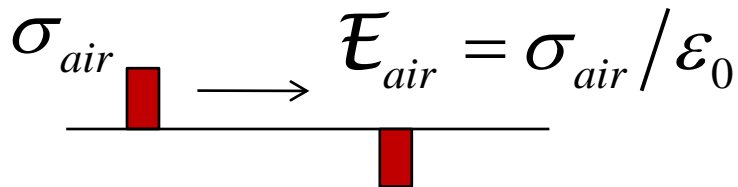
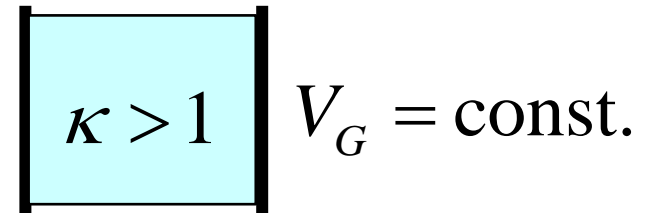
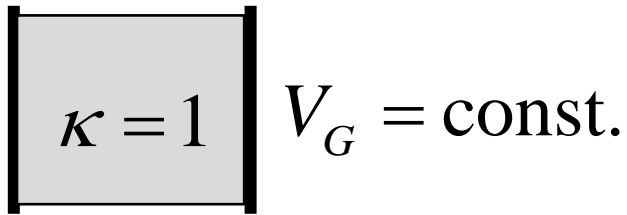
$$p = Q^* r = Q^* \{ r_0 + (x^+ - x^-) \} = [Q^* \times r_0] + \left[\left(\frac{Q^{*2}}{\gamma} \right) \times \mathbf{E}_{loc} \right]$$

Permanent dipole

Induced dipole

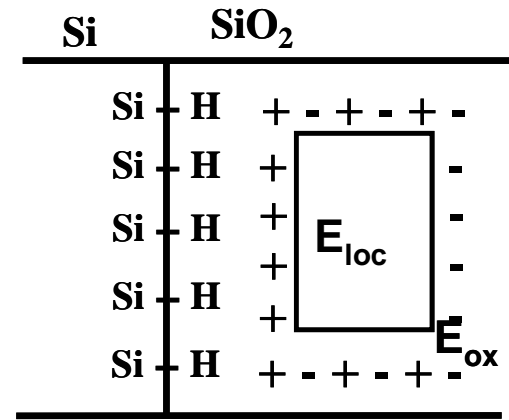
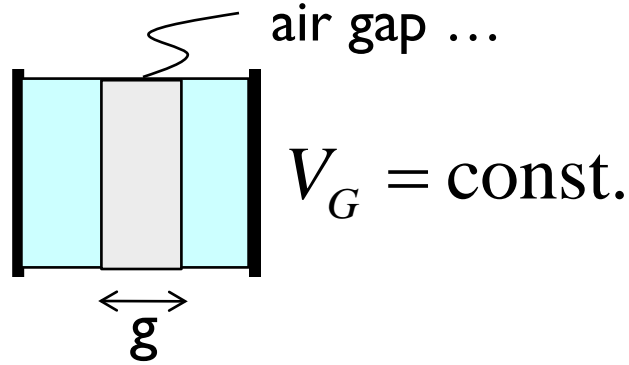
Aside: Calculation of E_{loc} from E_{ox}

$$\mathcal{E}_{ox} = V_G / T_{ox} \quad \text{for any dielectric ...}$$



$$\mathcal{E}_{air} = \mathcal{E}_{ox} \Rightarrow \sigma_{ox} = \kappa \sigma_{air}$$

E_{loc} vs. E_{ox} : Field enhancement in gaps



σ_{ox}^* \rightarrow $\mathcal{E}_{ox}^* = \sigma_{ox}^* / \kappa_{ox} \epsilon_0$

$$\mathcal{E}_{loc} \equiv \mathcal{E}_{air} = \kappa_{ox} \mathcal{E}_{ox}^* \cong \kappa_{ox} \mathcal{E}_{ox}$$

σ_{ox}^* \rightarrow $\mathcal{E}_{air} = \sigma_{ox}^* / \epsilon_0$

$$\because \mathcal{E}_{loc} g + \mathcal{E}_{ox}^* (T_{ox} - g) = V_G$$

$$\mathcal{E}_{ox}^* = \frac{V_G}{T_{ox} + (\kappa_{ox} - 1)g} \xrightarrow{g \sim 0} \mathcal{E}_{ox}$$

Strong enhancement of local field for an isolated bond in a gap

Calculation of E_{loc} from E_{ox}

$$\Delta U_{Si-H} \approx [Q^* \times r_o \times \mathcal{E}_{loc}] \equiv a \mathcal{E}_{ox}$$

$$\mathcal{E}_{loc} \cong \kappa \mathcal{E}_{ox}$$

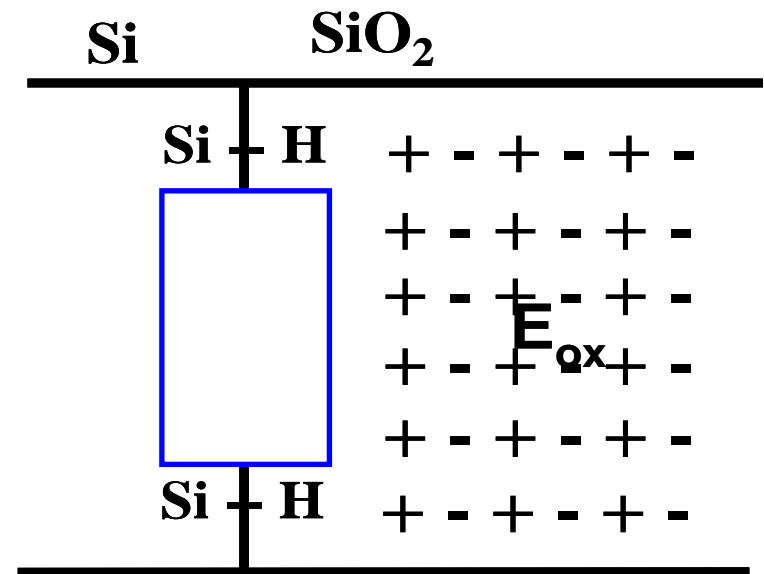
$$\Delta U_{Si-H} \approx [Q^* \times r_o \times \kappa \mathcal{E}_{ox}]$$

$$a = Q^* \times r_o \times \kappa \approx Q^* \times r_o \times \left(\frac{\kappa_{ox} + \kappa_{si}}{2} \right)$$

$$a = 0.15 * (4 + 12) / 2 = 0.9$$

$$N_{IT}(t) \propto \left(\frac{k_F N_0}{2k_R} \right)^{2/3} (D_{H_2} t)^{1/6}$$

$$\propto (p_h)^{2/3} e^{\frac{2\gamma_T E_{ox}}{3}} e^{-\frac{2(E_{F0} - aE_{ox})}{3k_B T}} e^{-\frac{E_A}{6k_B T}}$$



$$k_F = k_0 p_h T \sigma e^{-(E_{F0} - aE_{ox})/k_B T}$$

Putting back the pieces: Non-Arrhenius activation

$$N_{IT}(t) \propto \left(\frac{k_F N_0}{2k_R} \right)^{2/3} (D_{H_2} t)^{1/6}$$

$$k_F = k_0 p_h(\mathcal{E}_c) T(\mathcal{E}_{ox}) \sigma e^{-(E_{F0} - aE_{ox})/k_B T}$$

$$\Delta V_{IT} = \frac{q(\alpha \Delta N_{IT})}{C_{ox}}$$

$$k_R = k_{R0} e^{-(E_{R0})/k_B T}$$

$$N_{IT}(\mathcal{E}_{ox}, T, t) \propto (\mathcal{E}_c)^{2/3} e^{\frac{2}{3}\gamma_T \mathcal{E}_{ox}} e^{-\frac{2(E_{F0} - aE_{ox} - E_{R0})}{3k_B T}} e^{-\frac{E_A}{6k_B T}} t^{1/6}$$

$$\text{(for fixed T)} \propto (\mathcal{E}_c)^{2/3} e^{\frac{2}{3}\gamma \mathcal{E}_{ox}} t^{1/6} \quad \gamma \equiv \left(\gamma_T + \frac{a}{k_B T} \right)$$

$$\text{(for fixed field)} \propto e^{-\frac{E_A^*}{6k_B T}} t^{1/6}$$

$$E_A^* = 4(E_{F0} - aE_{ox} - E_{R0}) + E_A$$

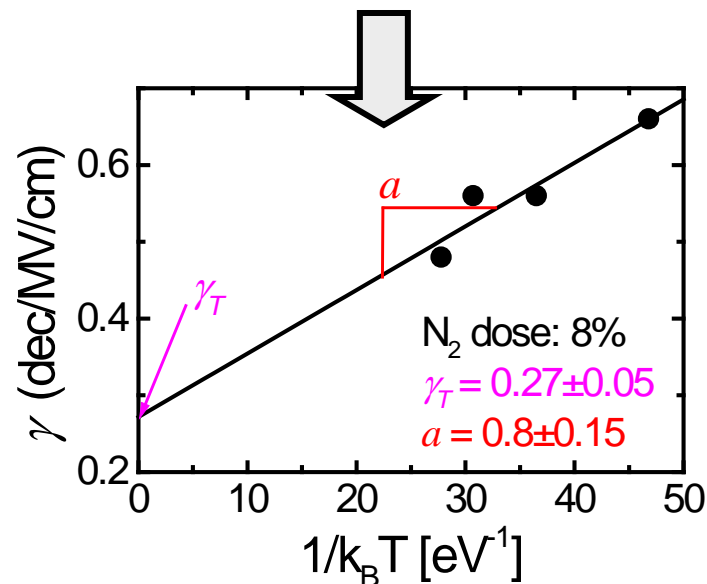
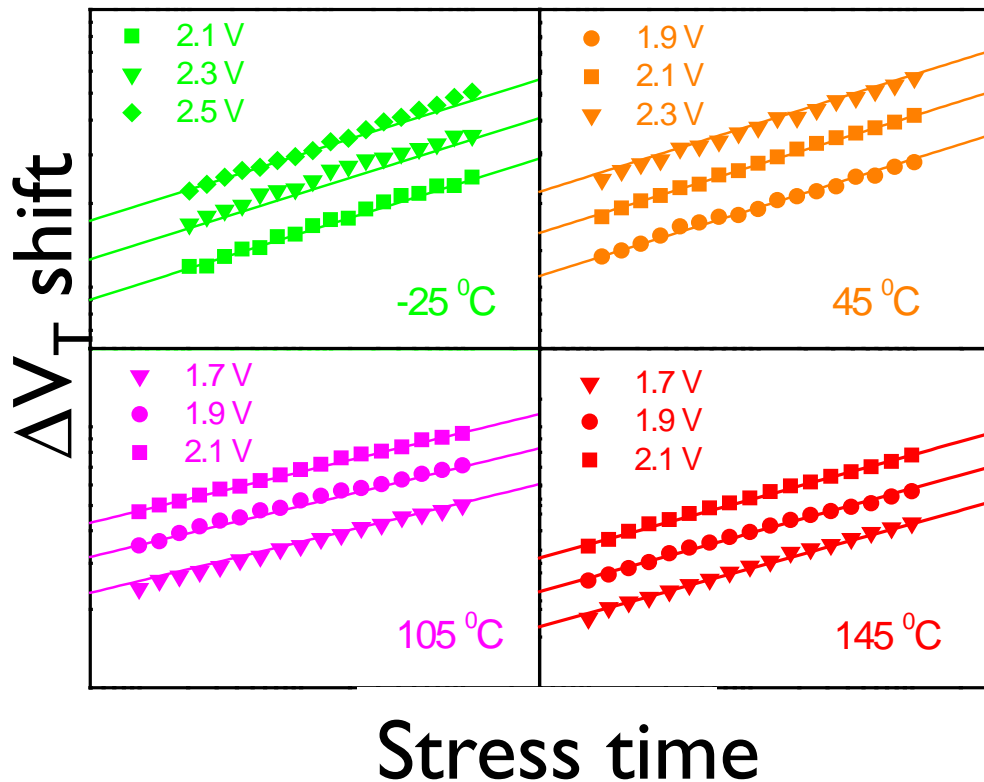
Outline

1. Background: Field dependent degradation
2. Components of field-dependent dissociation:
 - Tunneling
 - Hole density
 - Bond polarization factor
3. Interpreting experiments & voltage acceleration
4. Conclusions

Experiments for γ_T and a

$$\Delta V_T \sim |E_c|^{2/3} \exp(2\gamma E_{ox}/3) t^n$$

where, $\gamma = \gamma_T + a/k_B T$



From polarization
 $a = 0.6 \sim 1.2$

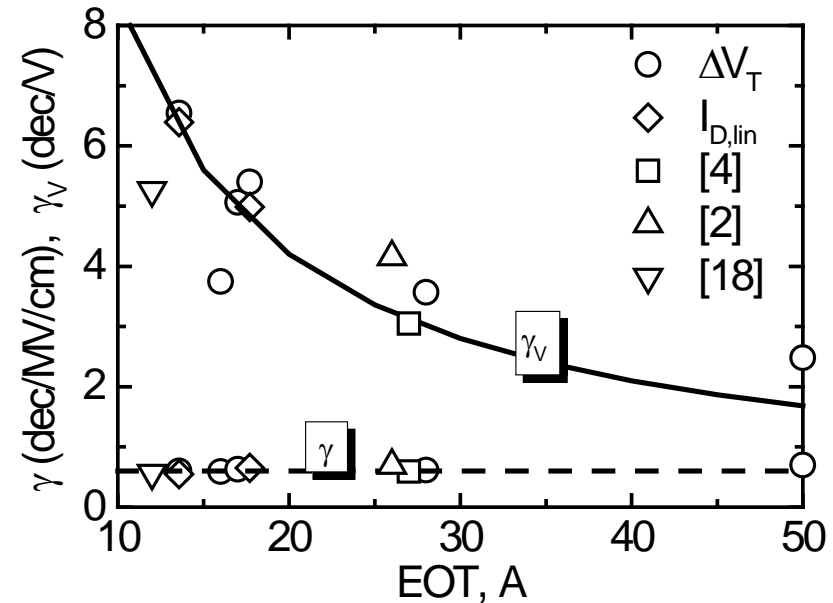
Voltage acceleration factors

To generate same number of defects at two different fields

$$E_1^{2/3} \exp(2\gamma E_1/3)t_1^n = E_2^{2/3} \exp(2\gamma E_2/3)t_2^n$$

$$\left(\frac{V_1}{V_2}\right)^{2/3} \exp\left[\frac{2\gamma(V_1 - V_2)}{3(EOT)}\right] = \left(\frac{t_2}{t_1}\right)^n$$

$$\gamma_V \text{ (in dec/V)} \approx \frac{\log_{10}\left(\frac{t_1}{t_2}\right)}{(V_2 - V_1)} = \frac{4\gamma}{2.3(EOT)}$$



Same voltage acceleration for all thicknesses

Conclusions

- We have discussed a simple theory of SiH bond dissociation based on the dielectric polarization. The theory appears consistent with experiments.
- NBTI phenomena has temperature-dependent voltage-acceleration and field-dependent temperature acceleration. Need careful analysis for determination of these important numbers.

Summary and Recommendation

1. Begin with a series of temperature, voltage, and duty cycle dependent experiments. Do not oversample, use on-the-fly or fast measurements (To be discussed in L17-20).
2. Decompose the contributions from interface defects and trapping. (See HW and Lectures 8-11)
3. Determine the time-exponents of individual components and compare with theoretical prediction.
4. Determine temperature activation energy by lateral scaling. Consider Arrhenius assumption carefully.
5. Determine polarization parameter **a** for field acceleration.
6. Now you have a complete model for NBTI degradation. Make projection and validate against long term data.

Self-Test Questions

- 1) Explain the difference between local field and global field within an oxide.
- 2) Explain physically why electric field decreases bond strength.
- 3) How does the dissociation process becomes non-Arrhenius?
- 4) Do you think the diffusion and repassivation will also become non-Arrhenius when field is applied? Why or why not?
- 5) Would field acceleration become smaller or larger for high-k dielectric for the same level of inversion charge?
- 6) Is NBTI a field-driven or voltage-driven phenomenon?
- 7) Can NBTI be described by classical voltage-independent voltage acceleration factors?